

Supplementary Information for

Integration of p-type β - In_2S_3 thin films on III-nitride heterostructures for multiple functional applications

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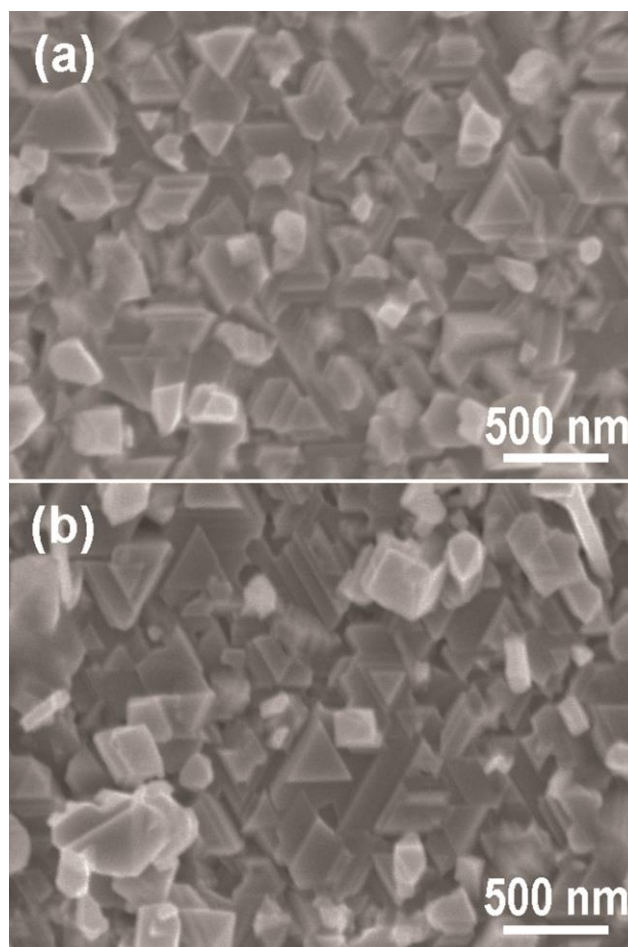


Figure S1 Typical SEM images recorded from InN thin films after thermal vapor sulfurization (TVS) at 700 °C (a) and 750 °C (b). The surfaces exhibit triangular facet structures without any distinguishable differences between (a) and (b).

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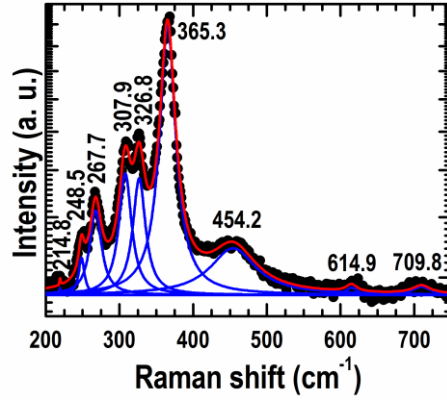


Figure S2 Raman-scattering spectrum and its feature fittings of InN thin film after thermal vapor sulfurization (TVS) at 700 °C. The spectrum was collected at room temperature using a 325-nm laser excitation.

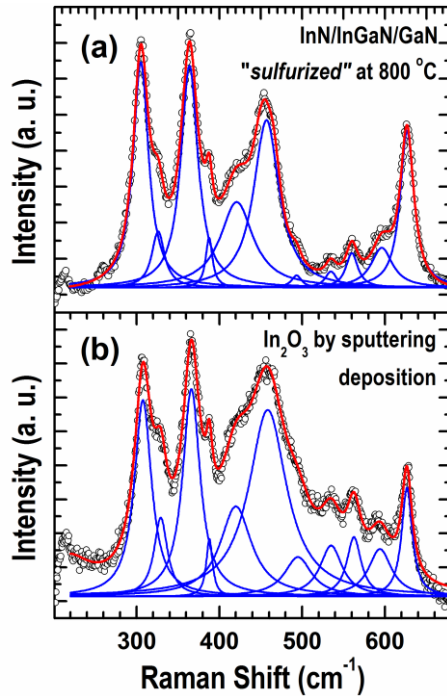


Figure S3 Raman spectra and their feature fittings: (a) InN thin film after thermal vapor sulfurization (TVS) at 800 °C and (b) In₂O₃ thin film deposited by magnetron-sputtering on GaAs (111) substrate at 350 °C (the deposition parameters can be found in Ref. 1). The similarity between the Raman spectra indicates an InN-to-In₂O₃ phase conversion occurred at $T = 800$ °C.

¹ H. F. Liu, G. X. Hu, H. Gong. Growth mechanism and optical properties of In₂O₃ nanorods synthesized on ZnO/GaAs (111) substrate. *J. Cryst. Growth*, **311**, 268 (2009).

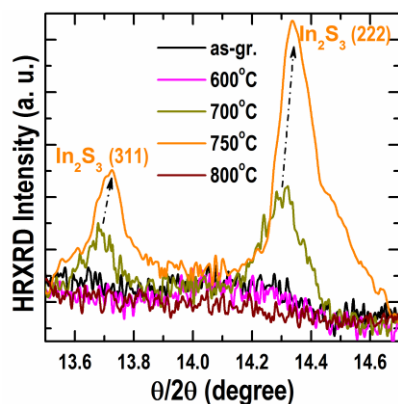


Figure S4 HRXRD $\theta/2\theta$ scanning patterns of InN thin film before and after thermal vapor sulfurization (TVS) at various temperature for 30 min; the patterns cover the diffractions from β - In_2S_3 (311) and (222) (JCPDS 65-0459) atomic planes. It is seen that the β - In_2S_3 (311) and (222) diffractions appeared at $T = 700$ °C, increased and shifted to larger angles at $T = 750$ °C (indicated by the arrows), and disappeared at $T = 800$ °C.

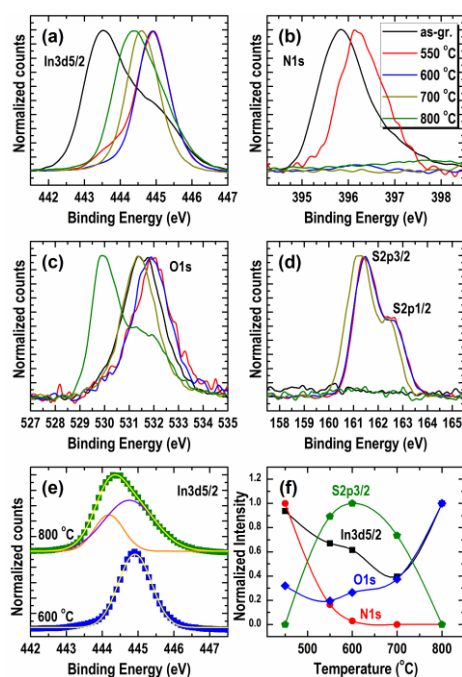


Figure S5 High-resolution XPS spectra of (a) $\text{In}3d_{5/2}$, (b) $\text{N}1s$, (c) $\text{O}1s$, (d) $\text{S}2p$, (e) comparison of $\text{In}3d_{5/2}$ for the samples after thermal vapor sulfurization (TVS) at 600 and 800 °C, and (f) peak intensity evolutions of $\text{N}1s$, $\text{O}1s$, $\text{In}3d_{5/2}$, and $\text{S}2p_{3/2}$ as a function of TVS temperature. Please note the disappearance of $\text{N}1s$ at $T \geq 600$ °C, indicating the surface passivation, rather than phase conversion, of InN at lower TVS temperatures.

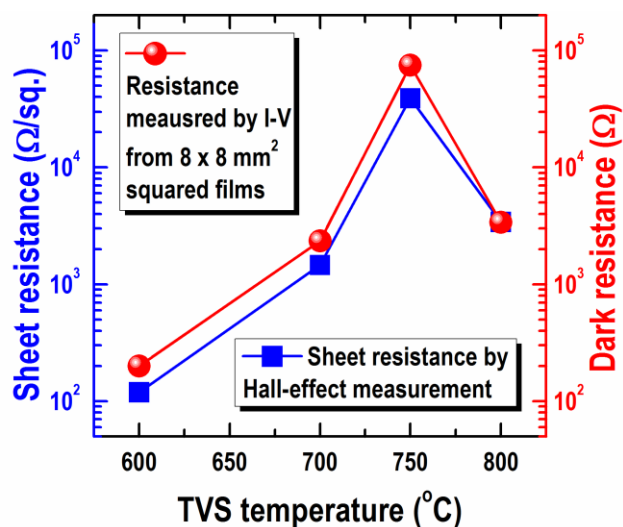


Figure S6 Correlation between sheet resistances measured by the Hall-effect method and dark-resistances of TVS-treated InN thin film samples; the dark-resistances were measured by I-V profiling from squared film of about $8 \times 8 \text{ mm}^2$.

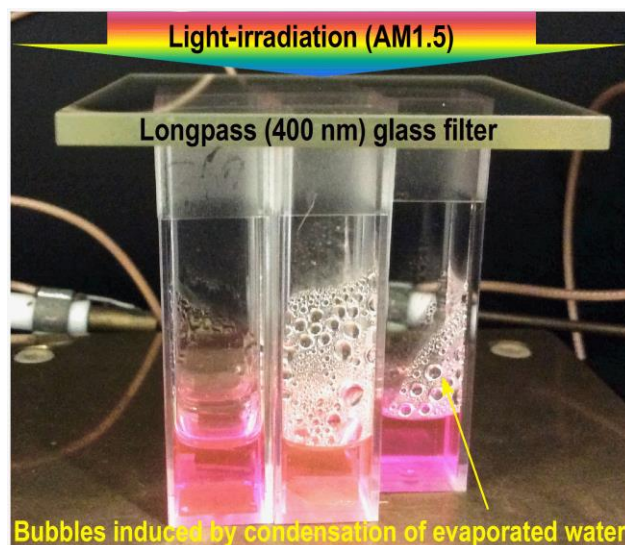


Figure S7 Photocatalytic reaction of RhB aqueous (1 ml, $2 \times 10^{-5} \text{ M}$) with and without the TVS-treated thin solid films. Bubbles induced by condensation of evaporated water are clearly seen on the inner wall of the cuvettes.